Amendment to the Claims:

This listing of claims will replace all prior versions, and listing, of claims in the application.

Listing of Claims:

1. (Withdrawn) A wire for a display device transmitting a scanning signal or a data signal, the wire comprising:

a metal film including a conductive material; and

a metal oxide film formed on the metal film and including an oxide of a conductive material.

- 2. (Withdrawn) The wire of claim 1, wherein the wire includes a gate line or a data line of a liquid crystal display.
- 3. (Withdrawn) The wire of claim 1, wherein the metal film comprises one of Cr, Mo, Mo alloy, Al and Al alloy.
- 4. (Withdrawn) The wire of claim 1, wherein the metal oxide film comprises one of oxides of Cr, Mo and Mo alloy.
- 5. (Withdrawn) The wire of claim 1, wherein the conductive material included in the metal film and the conductive material included in the metal oxide film are substantially the same.
 - 6. (Currently Amended) A thin film transistor array panel comprising:
- a gate wire formed on an insulating substrate and including a gate line and a gate electrode connected to the gate line;
 - a gate insulating film covering the gate wire;
 - a semiconductor layer formed on the gate insulating film;

a data wire formed on the gate insulating film or the semiconductor layer and including a data line, a source electrode connected to the data line and located on the semiconductor layer and a drain electrode formed on the semiconductor layer and located opposite the source

electrode with respect to the gate electrode;

a passivation layer covering the data wire; and

a pixel electrode including a transparent conductive material or a reflective conductive

material and connected to the drain electrode,

wherein the gate wire or the data wire comprises a metal film including a conductive

material and an opaque metal oxide film including an oxide of a conductive material,

wherein the opaque metal oxide film of the gate wire and the data wire block light, and

a side of the metal film is uncovered by the opaque metal oxide film.

7. (Original) The thin film transistor array panel of claim 6, wherein the metal film

comprises one of Cr, Mo, Mo alloy, Al and Al alloy.

8. (Previously Presented) The thin film transistor array panel of claim 6, wherein the

opaque metal oxide film comprises one of oxides of Cr, Mo, Mo alloy, Al and Al alloy.

9. (Previously Presented) The thin film transistor array panel of claim 6, wherein the

conductive material included in the metal film and the conductive material included in the

opaque metal oxide film are substantially the same.

10. (Original) The thin film transistor array panel of claim 6, wherein the gate wire

further includes a gate pad connected to the gate line, and the data wire further includes a data

pad connected to the data line, and the thin film transistor array panel further comprises:

a subsidiary gate pad including substantially the same layer as the pixel electrode and

connected to the gate pad; and

a subsidiary data pad including substantially the same layer as the pixel electrode

connected to the data pads.

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11. (Original) The thin film transistor array panel of claim 6, wherein the passivation

film comprises SiOC, SiOF, SiNx or an organic insulating material.

12. (Original) The thin film transistor array panel of claim 6, wherein the

semiconductor layer has substantially the same planar shape as the data wire excluding a

channel portion between the source electrode and the drain electrode.

13. (Original) The thin film transistor array panel of claim 6, wherein the pixel

electrode is located on the passivation layer, and the pixel electrode and the drain electrode are

connected to each other via a first contact hole provided in the passivation layer.

14. (Withdrawn) A method of manufacturing a wire for a display device, the wire

comprising: depositing a metal film on a substrate; depositing a metal oxide film on the metal

film; and patterning the metal oxide film and the metal film under substantially the same

etching condition to form a tapered structure.

15. (Withdrawn) The method of claim 14, wherein the metal film comprises Cr and the

metal oxide film comprises CrOx.

16. (Withdrawn) The method of claim 15, wherein the etching condition includes wet

etching using an etchant including 8-12% Ce(NH 4)2(NO3)6, 10-20% NH3 and remaining

ultra pure water.

17. (Withdrawn) A method of manufacturing a thin film transistor array panel,

comprising:

forming a gate wire on an insulating substrate, the gate wire including a gate line and a

gate electrode connected to the gate line;

forming a gate insulating film covering the gate wire;

forming a semiconductor layer including amorphous silicon;

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forming an ohmic contact layer including doped amorphous silicon on the

semiconductor layer;

forming a data wire on the gate insulating film or the semiconductor layer, the data wire

including a data line, a source electrode near the gate electrode, and a drain electrode located

opposite the source electrode with respect to the gate electrode;

forming a passivation layer covering the semiconductor layer; and

forming a pixel electrode electrically connected to the drain electrode,

wherein the formation of the gate wire or the formation of the data wire comprises:

depositing a metal film;

depositing a metal oxide film; and

etching the metal oxide film and the metal film under substantially the same

etching condition to make the gate wire or the data wire to have a tapered structure.

18. (Withdrawn) The method of claim 17, wherein the metal film comprises Cr and the

metal oxide film comprises CrOx.

19. (Withdrawn) The method of claim 15, wherein the etching condition includes wet

etching using an etchant including 8-12% Ce(NH 4)2(NO3)6, 10-20% NH3 and remaining

ultra pure water.

20. (Previously Presented) The thin film transistor array panel of claim 6, wherein the

opaque metal oxide film is formed on an entire top substantially horizontal surface of at least

one of the data wire and the gate wire.

21. (Previously Presented) The thin film transistor array panel of claim 6, further

comprising a plurality of color filters facing the pixel electrodes, wherein the plurality of color

filters block light.

22. (Previously Presented) The thin film transistor array panel of claim 21, wherein

portions of adjacent color filters of the plurality of color filters overlap with each other.

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23. (Previously Presented) The thin film transistor array panel of claim 6, wherein the

gate wire and the data wire transmits signals and block light leakage between pixel areas.

24. (Previously Presented) The thin film transistor array panel of claim 13, wherein the

drain electrode comprises the metal film and the opaque metal oxide film, and the pixel

electrode is connected to the metal film of the drain electrode.

25. (New) The thin film transistor array panel of claim 6, wherein the side of the

metal film includes opposing sidewalls defining the metal film and the sidewalls are uncovered

by the opaque metal oxide film.

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